

*a* priority from U.S. Patent Application No. 09/114,105, filed July 11, 1998; which application is a continuation-in-part of U.S. Patent Application No. 08/990,107, filed December 15, 1997, all of which are herein incorporated by reference in their entirety.

#### REMARKS

The above amendment has been made merely to clarify the priority claims in the subject application. No new matter has been added by way of this amendment. The Examiner is encouraged to contact Paul Parker at (206) 287-3258 should there be any questions regarding this amendment.

Respectfully submitted,

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Enclosure:

Appendix (Marked-up version of specification)

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## Appendix – Specification Marked to Show Changes

The present~~This~~ application is a continuation of prior International Application No. PCT/US99/15567, which was filed in English on July 9, 1999 and published as International Publication No. WO 00/02808, which in turn application claims priority to continuation-in-part of from U.S.S.N. 08/990,107, filed December 15, 1997, titled "Semiconductor Processing Apparatus Having Linear Conveyor System" and U.S.S.N. U.S. Application No. 09/114,105, filed July 11, 1998 entitled "Improved Robot for Microelectronic Workpiece Handling"; which application is a continuation-in-part of U.S. Patent Application No. 08/990,107, filed December 15, 1997, all of which are herein incorporated by reference in their entirety. The entire disclosures of both of the prior applications, as well as International Publication No. WO00/02808, are incorporated herein by reference.